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## BIB DATA SHEET

CONFIRMATION NO. 8166

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/587,427	07/26/2006 RULE	438	1792	Serie 6497		
<b>APPLICANTS</b> Eri Tsukada, Ibaraki, JAPAN; Christian Dussarrat, Ibaraki, JAPAN; Jean-Marc Girard, Paris, FRANCE;						
<b>** CONTINUING DATA *****</b> This application is a 371 of PCT/IB05/00170 01/19/2005						
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2004-025479 02/02/2004						
<b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 04/04/2007						
Foreign Priority claimed	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No	<input type="checkbox"/> Met after Allowance	STATE OR COUNTRY	SHEETS DRAWINGS	TOTAL CLAIMS	INDEPENDENT CLAIMS
35 USC 119(a-d) conditions met	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No	Initials	JAPAN	1	10	2
Verified and Acknowledged	/BRET P. CHEN/ Examiner's signature					
<b>ADDRESS</b> AIR LIQUIDE Intellectual Property 2700 POST OAK BOULEVARD, SUITE 1800 HOUSTON, TX 77056 UNITED STATES						
<b>TITLE</b> Method for producing silicon nitride films and silicon oxynitride films by chemical vapor deposition						
<b>FILING FEE RECEIVED</b> 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees		
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